## HeFIB2018

Helium and emerging Focused Ion Beams

		Monday	11011	<u> </u>	i aria	emerging Focused Tuesday	a loll be		13		Wednesday	
	Time <sup>·</sup>		Speaker		Time		Speaker		Time		Wednesday	Speaker
-		Break/refreshments		Analytic	08:30	Films	Notte	_		A revolutio	nary quantum computer device	
		Inivted Speaker			09:00	induced artifacts in polymer thin films: He vs. Ga  METALLOGRPHY OF THIN FILMS WITH	Allen	ation	08:50	fabricated t donor aton	from implanted ordered arrays of sin	Jamieson
		Sponsor contribution			09:20	FOCUSED ION BEAMS	Chiriaev	cts Nanofa	09:20	SET via lo	n Beam Mixing and Phase Separation  elopment for failure analysis – When	Xu
		Other			09:40	the HIM	Klingner		09:40	ions meet o	chémistry	Delobbe
						SIMS performed on the Helium Ion Microscope: a unique tool for highest spatial resolution imaging and correlative microscopy	Wirtz		10:00	other nano	lbeam suitability for circuit edit and machining applications	Greenzweig
	10:30	Welcome			10:20				10:20		Coffee	
_	10:40	Graphene nano-electro-mechanical (GNEM) devices functionalized by using helium ion beam	Mizuta	a lata litta	10:50		Kavanagh		10:50	films by foo	defect engineering in ferroelectric the cused ion beam microscopy	McGilly
2D Materials	11:10	Anderson localization of graphene by sub-nm diameter helium ion beam irradiation	Ogawa		11:20	Towards observing diffraction in a HIM	Herrmann			materials u simulations	duction in supported two-dimensiona inder ion irradiation from atomistic s: the substrate is crucial	Kretschme
Imaging and Biological applications	11:30	In-situ measurement of electron conduction modulation in graphene by helium ion beam irradiation	Nakaharai		11:40	Multi-Modal Characterization with Secondary Ion Mass Spectrometry on ZEISS ORION NanoFab	Casares		11:40	Fabrication	n of MoS2 with Helium Ion Beam: n of Gate-Tunable Memristor	Keane
		He-Ion Microscopy Combined with Micromanipulators for Pick & Place, Electrical & Mechanical Characterization, and Other Tasks	Smith			Characterising Carbon-based materials in the HIM: probing the invisible with secondary electror spectroscopy	Abrams		12:00	Nanoscale	of Gas Field Ion Source to Patternii Magnetic Structures	ng Bali
	12:10	Lunch			12:20	Lunch			12:20	Microscope	gnetic Domains with a Helium Ion e	Emmrich
	14:00	Helium and neon ion microscopy and milling for microbiological applications	Maasilta		14:00	Understanding Focused Ion Beam Sputtering and Gas-Assisted Etching via the EnviziON Monte Orario Simulation  Binary Collision Computer Simulation of FIB Induced Erosion and Atomic Mixing in Nanostructures	Mahady		12:40	S	Summary/Outlook	
	14:30	FIB/SEM Processing of Biological Samples	Wolff				Möller		12:50		Lunch	
	14:50	Correlative Microscopy with Light, Electrons and lons in Environmental Microbiology	Schmidt			Helium Ion Based Lithography of Advanced Resists	Feldman		14:30		on Boom Comton © US	/DD +
	15:10	Comparison of image fusion techniques for ion beam based correlative microscopy	Vollnhals		15:10	Advanced FIB nanopatterning employing a high precision sample stage	Bauerdick		17:00		Ion Beam Center @ HZD	
	15:30	Multimodal Imaging for Physical and Chemical Surface Characterization using a Combined Helium Ion Microscope and Secondary Ion Mass Spectrometry Platform	Ovchinnikova		15:30	Fabrication of Plasmonic Nanostructures by He+ and Ga+ Milling	Westphal					
	15:50	Coffee										
	16:20	ColdFIB – a new FIB column with a laser cooled source	Viteau									
		New non-Gallium FIB Alternatives for Nanofabrication	Mazarov									
Beams	17:10	Ion Sources for Focused Ion Beam Applications	Bischoff									
New Ion Beams	17:30	Source Shot Noise Mitigation in Helium Ion and Focused Ion Beam Microscopy	Murray- Bruce			Excursion and dinr	ier					
	17:50	The Xe plasma FIB - the other extreme	Mulders									
-	18:10	Revolutionary Field Emission Thruster Developments for Nano-satellites at TU Dresden and its correlative LMIS-applications at terrestrial Implanters.	Laufer									
=	18:30	Posters										
-	20:00	End of day 1 program	gram									